

	U	1	Document ID	Issue Date	Pages	Title	Current OR	Current XR	Retrieval C	Inventor	S	C	P	2	3		
1			US 2003010002	20031002	8	Epitaxially coated semiconductor wafer and method for producing same	428/141	257/E21.23		Wenski, Guido et al.							
2			US 20030045000	20030306	12	Semiconductor wafer with an improved structure and method for producing same	438/626			Wenski, Guido et al.							
3			US 20010047070	20011206	11	Process for the double-side polishing of semiconductor wafers	216/2	206/712;		Wenski, Guido et al.							
4			US 20010020101	20011108	12	Method for converting a wafer into a semiconductor wafer	438/471	257/E21.214		Wenski, Guido							
5			US 20010026707	20011101	6	Process for producing a semiconductor wafer	451/41	257/E21.23;		Fabry, Laszlo et al.							
6			US 20010044570	20010816	15	Process for producing a semiconductor wafer with a polycrystalline layer	451/41	257/E21.214;		Wenski, Guido et al.							
7			US 6752689	20040622	13	Apparatus for optical inspection of wafer during a process	451/6	156/345.13;		Finarov, Moshe							
8			US 6739944	20040525	25	System for real-time control of semiconductor wafer polishing	451/5	451/10;		Sandhu, Gurtej S. et al.							
9			US 6700081	20040223	21	Method and apparatus for polishing a semiconductor wafer	439/602	257/E21.220		Grabbe, Alvaro et al.							

9 and (separat\$ near device wedge
adj shap\$3)

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